Analytical SEM Solutions for Geology – Part I



Webinar, August 13, 2019

Presenters in Part I



SEM for Geological Applications - important aspects to consider Mats Eriksson Department Manager Hitachi High-Technologies



Advanced Microanalysis with the QUANTAX System Max Patzschke Application Specialist Bruker Nano Analytics



Macro-Micro-Nanoscale SEM/EDS of Earth and Planetary Materials

Dr. Tobias Salge Electron Probe Microanalyst Imaging and Analysis Centre, Natural History Museum, London, UK



SEM(s) for Geological Applications

- important aspects to consider



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- Introduction to SEM
- Signals detected
- Electron sources
- Chamber and stage
- Variable pressure / low vacuum
- Imaging requirements in geology
- Finding the area of interest

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Basic operation of the SEM

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Imaging signals in the SEM, SE/BSE emission

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Imaging signals in the SEM, SE/BSE emission













Beam Excitation Volumes





Monte Carlo simulation Comparison of scattering region of incident electrons (Sample : Si)



Electron Source Comparison



Source size $1-2 \mu m$ $1-2 \mu m$ $10-25 nm$ $3-5 nm$ $3-5 nm$ Temperature $2300^{\circ}C$ $1500^{\circ}C$ $1500^{\circ}C$ $R.T.$ $R.T.$ $R.T.$ Brightness 1 10 500 1000 1500 $[A/cm^2sr]$ 10^6 10^7 $5x10^8$ $1x10^9$ $2x10^9$ Energy spread $2.0 eV$ $1.5 eV$ $0.5 eV$ $0.2 eV$ $0.2 eV$ Stability [%/hr] $<1\%$ $<2\%$ 0.2% $3-5\%$ 0.8% Emission $200 \mu A$ $100 \mu A$ $100 \mu A$ $10 \mu A$ $20 \mu A$ Probe current $1 \mu A$ $1 \mu A$ $20 n A$ $20 n A$ $20 n A$ Life time $1 month$ $1 year$ $2 years$ $>5 years$ $>5 years$	Emitter	W	LaB6	Schottky FE	Cold FE	New Cold FE	
Temperature 2300° C 1500° C 1500° CR.T.R.T.Brightness110 500 10001500 $[A/cm^2sr]$ 10^6 10^7 $5x10^8$ $1x10^9$ $2x10^9$ Energy spread $2.0 eV$ $1.5 eV$ $0.5 eV$ $0.2 eV$ $0.2 eV$ Stability [%/hr] $<1\%$ $<2\%$ 0.2% 3.5% 0.8% Emission $200 \mu A$ $100 \mu A$ $100 \mu A$ $10 \mu A$ $20 \mu A$ Probe current $1 \mu A$ $1 \mu A$ $200 n A$ $20 n A$ $20 n A$ Life time $1 month$ $1 year$ $2 years$ $>5 years$ $>5 years$	Source size	1 – 2 μm	1 – 2 μm	10-25 nm	3-5 nm	3-5 nm	25
Brightness11050010001500 $[A/cm^2sr]$ 106107 $5x10^8$ $1x10^9$ $2x10^9$ Energy spread $2.0 eV$ $1.5 eV$ $0.5 eV$ $0.2 eV$ $0.2 eV$ Stability [%/hr]<1%	Temperature	2300°C	1500°C	1500°C	R.T.	R.T.	LaB6 fi
$[A/cm^2sr]$ 10^6 10^7 $5x10^8$ $1x10^9$ $2x10^9$ $4x10^9$ $2x10^9$ Energy spread $2.0 eV$ $1.5 eV$ $0.5 eV$ $0.2 eV$ $0.2 eV$ $0.2 eV$ Stability [%/hr] $< 1\%$ $< 2\%$ 0.2% $3-5\%$ 0.8% Emission $200 \mu A$ $100 \mu A$ $100 \mu A$ $10 \mu A$ $20 \mu A$ Probe current $1 \mu A$ $1 \mu A$ $200 n A$ $20 n A$ $20 n A$ Life time $1 month$ $1 year$ $2 years$ $>5 years$ $>5 years$	Brightness	1	10	500	1000	1500	SE LaBe
Energy spread 2.0 eV 1.5 eV 0.5 eV 0.2 eV 0.2 eV W filamerStability [%/hr] $< 1\%$ $< 2\%$ 0.2% $3-5\%$ 0.8% U filamerEmission $200 \mu A$ $100 \mu A$ $100 \mu A$ $10 \mu A$ $20 \mu A$ U filamerProbe current $1 \mu A$ $1 \mu A$ $200 n A$ $20 n A$ $20 n A$ $20 n A$ Life time 1 month 1 year 2 years $>5 \text{ years}$ $>5 \text{ years}$	[A/cm ² sr]	10 ⁶	10 ⁷	5x10 ⁸	1x10 ⁹	2x10 ⁹	
Stability [%/hr] < 1% < 2 % 0.2% $3-5\%$ 0.8% 100μ Emission 200μ A 100μ A 100μ A 10μ A 20μ A 100μ A 10μ A 20μ A 100μ A 10μ A 20μ A 100μ A 10μ A 20μ A 100μ A 10μ A 20μ A 100μ A 10μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 100μ A 20μ A 100μ A 20μ A 100μ A<	Energy spread	2.0 eV	1.5 eV	0.5 eV	0.2 eV	0.2 eV	W/ filomont
Emission $200 \ \mu A$ $100 \ \mu A$ $100 \ \mu A$ $10 \ \mu A$ $20 \ \mu A$ $20 \ \mu A$ Probe current $1 \ \mu A$ $1 \ \mu A$ $200 \ n A$ $20 \ n A$ $20 \ n A$ $20 \ n A$ Life time $1 \ month$ $1 \ year$ $2 \ years$ >5 years>5 years	Stability [%/hr]	< 1%	< 2 %	0.2%	3-5%	0.8%	SE Tungsten
Probe current1 μA1 μA200 nA20 nA20 nA20 nALife time1 month1 year2 years>5 years>5 years	Emission	200 µA	100 µA	100 µA	10 µA	20 µA	
Life time 1 month 1 year 2 years >5 years >5 years	Probe current	1 µA	1 µA	200 nA	20 nA	20 nA	obe size
	Life time	1 month	1 year	2 years	>5 years	>5 years	ŭ

limit

10⁵ 10⁶ 10⁷ 10⁸ 10⁹ 10¹⁰ Copyright ©2018 Hitachi High-Technologies Corporation All Rights Reserved. Source Brightness B (A/cm²/sr)

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Detection system for various signals



Specimen: Solar Cell incl. fluorescent material, V_{acc}: 3kV

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Cathodoluminescence using the UVD detector





BSE



10 kV, 350 X

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Flexible chamber, ports and stage



- Enough ports for potential accessories EDS(s), WDS, EBSD, CL(s), µXRF, substages, …
- Geometry where EBSD sits 90 degrees from tilt axis
- True eucentric stage, so that you move (XY) in the tilted sample plane
- Space for several EDS detectors from different directions (topography, speed)

- XY travel to be able to cover you largest sample or sample holder
- Ability to handle high samples
- Stable enough for heavy samples
- Sample holder to allow stable mounting

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Low vacuum / Variable pressure operation

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Utilizing a low vacuum environment can allow observation of water or oil based specimens in a natural state. The positively charged ions originated from the residual gas molecules generated by electron beam neutralize negatively charged electrons impinged on the specimen surface. Low vacuum observation eliminates traditional sample preparation requirements such as specimen dehydration or metal coating.



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Low vacuum / Variable pressure operation

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Charge free observation without metal coating of non-conductive specimen possible.



High Vacuum mode without metal coating : Image distortion due to surface charging

Metal coating, such as Au or Pd absorbs SE, BSE, and X-ray signals from the specimen and weaken SEM detectable signals.



Observation with metal coating : Material contrast of Ti (arrowed) is reduced by metal coating. No peak overlapping X-ray analysis is possible without metal coating.



EDS Spectrums with metal coating : Spectrums of Zr and Pt (coating material) are overlapped.



Low Vacuum mode without metal coating : Less specimen surface charging.



Observation without metal coating : Clearer material contrast of Ti (arrowed) at low vacuum mode



EDS Spectrums without metal coating : Spectrums of Zr can be clearly identified

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Low-vacuum versus high-vacuum: No difference in FoV and current **Inspire the Next**



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Finding the area of interest

Navicam built into dedicated chamber port.

Automatic image acquisition during chamber evacuation



Automatically acquired picture of the sample holder and samples

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Camera image transferred to the SEM-MAP for navigation Copyright ©2018 Hitachi High-Technologies Corporation All Rights Reserved.

Low mag - Depth of focus

For many applications low magnification is more important than resolution.

- To easily find where you are on the sample
- Easy correlative microscopy
- Taking overview images and EDS-maps

When you have rough or tilted samples (EBSD) depth of focus and potential distortions becomes critical



30mm long screw on SU5000 sample holder *Hitachi High-Tech*



Low distortion at low mag on tilted samples



Critical for large area EBSD measurements

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at 70 degrees tilt

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Easy imaging and analysis at the same WD and settings



Dedicated use of left screen for image display Easy image comparison by signal type 6 x identical picture size

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Operation related windows are moved to the right screen for improved usability. SEM-MAP and chamber scope images can also be displayed.

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Thank you !



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Advanced Microanalysis With The QUANTAX System



Max Patzschke







- Introduction to QUANTAX Electron Microscope Analyzers
- EDS maps with overlapping lines (S, Pb and Mo)
- Annular FlatQUAD detector for EDS
- Fast maps using the FlatQUAD detector
- AMICS automated mineral classification and identification software
- Summary

Bruker Nano Analytics Division EM Analyzers





Bruker Nano Analytics Division EM Analyzers









Peak intensity maps: an element is displayed by the number of total counts in a predifined energy region around the peak.

Peak overlaps of different elements



Element	Interferences	Δ eV	Samples or applications where the
and line	with		overlaps are found
Cu-L	Νа-Кα	18	Biological samples (grid)
As-L	Νа-Кα	79	Biological samples (stain or fixative)
Ag-L	CI-Kα	10	Biological samples (stain or fixative)
Ru-L	S-Kα	54	Biological samples (stain or fixative)
Os-M	Al-Kα	5	Biological samples (stain or fixative)
U-M	Κ-Κα	22	Biological samples (stain or fixative)
Sr-La	Si-Kα	31	Silicates (feldspars in particular)
Υ-Lβ	Ρ-Κα	18	Phosphates
Υ-Lβ	Zr-Lα	46	Silicates (zircon), oxides (zirconia)
<mark>S-Κα,</mark> β	Mo-Lα; Pb-Mα	14; 38	Minerals, lubricants, sulfides, sulfates
Τί-Κβ	ν-κα	20	Steels, Fe-Ti oxides
V-Kβ	Cr-Kα	13	Steels
Cr-Kβ	Mn-Kα	47	Steels
Mn-Kβ	Fe-Kα	87	Steels
Fe-Kβ	Co-K α	128	Steels, magnetic alloys
Co-K β	Νί-Κα	169	Steels, hard surfacing alloys
W-Mα,β	Si-Κα,β	35	Semiconductor processing
Τа-Μα,β	Si-Κα,β	27	Semiconductor processing
Τί-Κα	Ba-Lα	45	Optoelectronics, silicates
As-Kα	Pb-Lα	8	Pigments

Overlaps known from biological, geological and material sciences and industries

Modified after Goldstein et al. (2007). Scanning Electron Microscopy and X-Ray Microanalysis. Springer







Peak intensity maps show same distribution for elements with overlapping energies!











Peak intensity maps show same distribution for elements with overlapping energies!

What to do?









Peak intensity maps show same distribution for elements with overlapping energies!

What to do?

Need Deconvolution of peak intensities of the map!







ESPRIT for EDS Deconvolution of peak intensities





Impulses of the spectra are correlated to identified elements. An "experimental" spectrum is compiled and compared with the acquired spectrum.







Same map data of elements with **overlapping peaks**. Different interpretations:

Peak intensity map:

Fake element distribution!

Net intensity (deconvolved) map:

Correct distribution of elements















Bruker Nano Analytics Division EM Analyzers





ESPRIT for EDS with the FlatQUAD Advantage of high take-off angle and annular design



Take-off angle comparison: XFlash[®] 5060FQ vs. conventional SDDs:



Ω > 1.1 sr

ESPRIT for SEM-EDS Hypermapping: Image Extension







Image Extension

- Use actual sample position as central Mapping position and define number of x/y frames around
- Result: **one** Hypermap file
- Image extension can be enlarged for a full sample map with more than 20,000 x 15,000 pixels

ESPRIT for EDS with the FlatQUAD Large area Hypermap



- Image Extension Map with 10x10 fields stitched automatic together
- FOV 18.1mm
- Aquired at 15kV,




ESPRIT for EDS with the FlatQUAD Large area Hypermap



- Image Extension Map with 10x10 fields stitched automatic together
- FOV 18.1mm
- Aquired at 15kV,
- 3 s per field (406 s total mapping time)
- ICR: 880 kcps



ESPRIT for EDS with the FlatQUAD Large area Hypermap



- Image Extension Map with 10x10 fields stitched together
- Aquired at 15kV,
- 3 s per field (406 s total time)
- ICR: 880 kcps











ESPRIT for EDS with the FlatQUAD Large area Hypermap



- Complete offline data processing
- Spectrum storage for each pixel

cps/e











ESPRIT for EDS with the FlatQUAD Silica nanoparticles



XFlash FlatQUAD, 5 kV, 520 pA, 22.5 kcps, 250x250 pixel, 2 nm pixel size, 377 s



K. Natte, T. Behnke, G. Orts-Gil, C. Würth, J. F. Friedrich, W. Österle and U. Resch-Genger, J Nanopart Res, 2012, 14, 680



ESPRIT for EDS with the FlatQUAD Silica nanoparticles



XFlash FlatQUAD, 5 kV, 520 pA , 22.5 kcps, 250x250 pixel, 2 nm pixel size, 377 s



Rades et al









AMICS for QUANTAX – EDS on SEM



AMICS - easy to configure measurement area by definable sample block holders

And can perform the following

- Particle
- Mapping
- BSE Image acquisition
- Standards acquisition
- Bright Phase Search

Controls SEM settings, moves stage to each position and acquires images through the QUANTAX system.





AMICS is easy to configure measurement area by definable sample block holders

And can perform the following

- Particle
- Mapping
- BSE Image acquisition
- Standards acquisition
- Bright Phase Search

Controls SEM settings, moves stage to each position and acquires images through the QUANTAX system.



Frame (BSE Image)

Area



AMICS will allow setting background thresholds and will create a mask for the particles.

When combined with mapping, particle can be mapped, e.g. with a step size of 5 μ m.

In particle mode, computer vision techniques allow grey level variation and segment size to be adjusted to segment particles. Each segment (above a set size) will be analyzed by a single X-ray spot

X-ray spectra acquisition is via the QUANTAX system.





Mineral identification:

For each point or segment a spectrum is acquired, analyzed and classified live – using the specified species list.

A live distribution of minerals can be seen during measurement.

All the data is saved progressively and modal data by area and wt % and segments measured is updated after each completed frame.

Processing and reclassification of data is done post measurement in order to create images, charts and tables for reports.



AMICS for QUANTAX EDS Advantage of AMICS



One-click built-in calculations

- Can view as data table
- Or chart
- Or image grid

Modal Mineralogy								
	Name	Wt%	Area%	Area (µ2)	Particle Num	Grain Number	Relative Error	
2	<al></al>	<all></all>	<all></all>	<all></all>	<all> 🔎</all>	<all></all>	<all> 🔎</all>	
1	Quartz	6.20	7.32	784575.10	1	931	1.87	
2	Andesine	21.93	25.37	2721339.45	1	1067	1.87	
3	Ferrohomble	48.03	46.09	4942962.19	1	666	1.87	
4	Biotite	9.97	9.74	1044473.43	1	2051	1.87	
5	Ilmenite	7.24	4.74	508612.79	1	467	1.87	
6	Apatite	4.58	4.44	476034.98	1	205	1.87	
7	Epidote	0.66	0.60	63998.02	1	403	1.87	
8	Chlorite	0.39	0.38	40686.61	1	547	1.87	
9	Other	0.61	0.58	62555.11	1	712	1.87	
10	Unknown	0.39	0.74	79395.40	8	2864	0.00	











- With the Bruker QUANTAX System: Samples can be investigated using different techniques at the same SEM, with the same software without changing the sample
- Combining WDS, EBSD and Micro-XRF with EDS overcomes the physical limit for EDS
- Enhanced atomic library from Bruker allows deconvolution and quantification of strong overlapping elements
- FlatQUAD detector allows measurements on beam sensitive samples, with topography, as well as high speed mappings for big areas and nanoparticles
- AMICS Minerals with similar BSE intensities can be effectively distinguished with AMICS's unique advanced segmentation
- AMICS A number of predefined calculations are available, which can be displayed in tabular, image grid or chart formats



Innovation with Integrity

Macro-Micro-Nanoscale SEM/EDS of Earth and Planetary Materials

T. Salge, J. Spratt, S. Russell, R. Neumann, T. Mohr-Westheide, A. Greshake, W. U. Reimold, L. Ferrière



SEM and EDS Introduction

- SEM imaging
 - Secondary and back-scattered electrons
 - ➔ Variable pressure mode
- EDS microanalysis
 - Standards-based quantification
 - Advanced hyperspectral imaging techniques
- Novel analytical approaches
 - Macroscale analysis using automatic stage control
 - Sub-micron spatial resolution by low energy analysis
 - Non-destructive analysis using ultra-low beam currents

Sample preparation High vaccuum and VP mode SEM analysis

- To inhibit charging, non-conductive samples are usually coated.
- Gold or palladium improves the SE signal for topographic imaging.
- Carbon coating is preferred for X-ray analysis.



- Uncoated samples can be analysed at ~10 Pa to 400 Pa.
- Collisions of the electron beam with gas molecules create positive ions.
- These migrate to negatively charged areas of the specimen and neutralise the surface charge.

VP-SEM Micronalysis Beam skirting



- Remote generation of X-rays by electrons scattered out of the focussed beam.
- Reduces the spatial resolution for X-ray microanalysis.
- Contributions from the environmental gas.



Salge et al. (2018)



- Polymer window
 - Analysis of low energy X-ray lines
- SDD
 - ➔ No liquid N₂ cooling
 - High process count rates (up to 600 kcps)
- Conventional geometry
 - Shadowing effects
 - Multi detector option
- Annular SDD
 - No shadowing effects
 - → 10-100 times higher sensitivity



Annular SDD – comparison of crater area coverage



• Annular design, ~1sr, 4 detection units, 2.4 Mcps OCR





Kearsley et al. (2013), Terborg et al. (2017)

Standards-based Quantification Requirements

- Samples: polished, perpendicular aligned, carbon coated
- References: similar matrix, high element concentration
- Same operating conditions (HV, beam current, WD)
- Beam current must be monitored (SEM has no current regulator)
- Vacuum pump for the electron gun improves beam stability and operating time (1000's of hours).



- 1 Filament and accelerating voltage on
- 2 Beam current quickly drops
- 3 Beam alignment using shift and tilt coils
- 4 Beam current slowly drops
- 5 Beam alignment using shift and tilt coils
- 6 Beam stabilises

Salge et al. (2018)

Standards-based Quantification Limit of Detection (LOD)

- LOD depends on the counts in the peak above the background.
- Typical LOD EDS ~0.1 mass% (WDS: ~0.02 mass%)



Standards-based Quantification Impulse statistics

	n	Na	Mg	Al	Si	Ca	Ti	Cr	Mn	Fe	0	Total
WD-EPMA	21	1.01	9.88	4.17	23.7	11.5	0.51	0.11	0.11	4.91	44.0	99.9
s (\pm mass%)		0.02	0.07	0.07	0.06	0.07	0.01	0.01	0.01	0.03	0.11	
EDS 50 k	12	0.92	9.93	4.29	23.5	11.8	0.58	(0.17)	(0.12)	4.89	44.1	100.3
s (± mass%)		0.10	0.20	0.14	0.30	0.29	0.10	0.07	0.09	0.29	0.41	
EDS 1000 k	12	0.89	9.89	4.21	23.5	11.6	0.50	0.17	0.09	4.99	43.8	99.6
s (± mass%)		0.04	0.04	0.03	0.07	0.05	0.02	0.02	0.03	0.04	0.15	

NMNH 122142 Augite, Kakanui, NZ, 20 kV, ~8 kcps, SDD, W-SEM

- Better impulse statistics results to a lower deviation of mean values and improved precision.
- EDS can achieve precise and accurate results (4 year old calibration).
- For elements with low concentration and significant peak overlaps in EDS spectra, WDS can obtain better results (better spectral resolution, superiour signal to noise ratio).

Spectrum Imaging Advanced EDS

- → Improved element ID
- ➔ Modal analysis





Polymetallic iron ore Maximum Pixel Spectrum

Synthetic spectrum of highest count level found in each spectrum channel

cps/e\

Detection of elements present in some pixel





Comparison of sum spectrum and MaxPixSpec

20 kV, 220 kcps, 132 min 0.47 μ m pixel size, 700x604 pixels 30 mm² SDD, FE-SEM

Niobium, zirconium and titanium had not been targeted by conventional wet-chemical analysis, but were identified by the Maximum Pixel Spectrum function.

Salge et al. (2013)

Polymetallic iron ore Pixel spectra and quantitative mapping

BSE overlain with quantified element map (mass%)



Zircon inclusions

Fe(Mn) columbite



One pixel spectra (~2,000 counts in the complete spectrum)





Mapping options Intensity and chemical phase map

Composite intensity map



 Iron oxides can be recognized by composite intensity maps of oxygen and iron.

Chemical phase map



 Autophase result with consideration of oxygen, iron and silicon.

	Area [µm²]	Area [Pixels)	Area [%]
Hematite	61360	277004	65.5
Magnetite	31418	141834	33.5
Silicate	877	3960	0.9
Unassigned	<1	2	<0.1

High Resolution Imaging at the Macroscale Automatic stage control

- Acquisition of several datasets over a larger area
- Montaging of individual datasets to one file at high pixel resolution
- SEM: Giga pixels / EDS: 10's of mega pixels
- Sub-micron spatial resolution by low energy analysis



Salge et al. (2018)

Lunar meteorite Dhofar081



20 kV, 2 μm pixel size, 22 MP, 7295 x 2986 pixels, 480 fields

10 kV, 0.5 μm pixel size, 21 MP, 6851 x 3058 pixels, 28 fields

Salge et al. (2018)

Too much

• Information?

- Measurement Time?
- Evaluation Time!

Automated feature analysis Image Analysis and Chemical Classification

Particle sample (BSE Image)

Image binarization

Automatic detection of particles and image analysis \rightarrow particle morphology (area, length, width, aspect ratio, diameter, ...)

Automated collection of EDS spectra (each particle) \rightarrow quantification of EDS spectra

Classification of particles based on pre-defined chemical groups

Review, data analysis and reporting









Extraterrestrial carrier phases at ICDP BARB5 drill core Cr-Ni spinel cluster associated with PGE phases



BSE mosaic (100 nm pixel resolution, 6103x4065 pixels)

Mohr-Westheide et al. (2015)

Extraterrestrial carrier phases at ICDP BARB5 drill core Cr-Ni spinel cluster associated with PGE phases

BSE mosaic (100 nm pixel resolution, 6103x4065 pixels)

Mohr-Westheide et al. (2015)

Automated feature analysis Cr-Ni spinel and PGE phases

- Impact spherule layers at the ICDP BARB5 drill core.
- Ni-Cr spinel cluster are associated with sub-micron-sized PGE-rich metal alloy and PGE sulpharsenides

Analysis	Cr-Ni spinel	PGE	
BSE threshold	Intermediate to bright	bright	
Pixel resolution	~2 µm	~100 nm	
Accepted particles	6 µm radius	250 nm radius	
HV	20 kV	6 kV	
Input count rate	~90 kcps	~70 kcps	
Spectrum acquisition time	0.5 s	3 s	
Fielde	288	170	
rieius	(400x266 pixels)	(3600x2397 pixels)	
Count	707	38	
Total time	60 min	90 min	



2 cm

511.29 mH

shale

Е

shale

Automated feature analysis Cr-Ni spinel and PGE phases

museum für naturkunde berlin



Energy [keV]

Low kV analysis at the sub-micron scale Challenges

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Peak overlaps

- Separation by peak deconvolution
- Net intensities

Contamination

- Deposition of hydrocarbon
- Preventing by cold trap

Samples drift

- Sample heating
- Drift compensation by SEM image comparison





Salge et al. (2018)

Low kV analysis at the sub-micron scale Net intensity map

museum für naturkunde berlin

EDS deconvolution algorithms allows the analysis of overlapping peak in the low and intermediate energy range.



6 kV, 52 min, 8 kcps, 30.6 nm pixels, 10 mm² SDD, FE-SEM

Salge et al. (2018)
Microanalyst's Dream

- Non-destructive, non-invasive analysis (no polishing, no coating, reducing carbon contamination)
- High sensitivity of the annnular SDD
- Ultra-low beam current (~10 pA) at high vacuum

Planetologist's Dream

Samples "Out of Space"



High vacuum analysis at low beam current Historic stony meteorite ("Mocs")



SE C-K O-K Pb-MA S-KA 10 111 HV: 6kV

Annular SDD, 6 kV, <10 pA, 2 kcps, 130 nm pixel size, 15 h

- Fell 3rd February 1882
- Sample preparation (coating) exluded
- Lead (old polishing) is deposited on top of silicates
- 2. Contamination with soot by heating with coal-fired furnaces



© Microscopy Society of America 2017, published by Cambridge University Press.

High vacuum analysis at low beam current Historic stony meteorite ("Mocs")



Annular SDD, 6 kV, <10 pA, 2 kcps, 130 nm pixel size, 15 h



EDS at high vacuum offers better spatial resolution compared to low vacuum



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Summary Advanced SEM-EDS

Hyperspectral imaging techniques

➔ Enhance element ID and chemical phase analysis.

Low voltage EDS

➔ Enhances the spatial resolution to the sub-micron scale.

Automatic stage control

- → Allows to acquire datasets at the macroscale.
- Classification of minerals over short measurement times by feature analysis.

Annular SDD

Provides high spatial resolution and high detection sensitivity without the necessity of applying a conductive coating or working in low vacuum.

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